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EXAMINER

MOVVA, AMAR

ART UNIT

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PAPER

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

DETAILED ACTION

Claim Rejections - 35 USC § 112

1. The following is a quotation of the first paragraph of 35 U.S.C. 112:

The specification shall contain a written description of the invention, and of the manner and process of making and using it, in such full, clear, concise, and exact terms as to enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to make and use the same and shall set forth the best mode contemplated by the inventor of carrying out his invention.

2. Claims 1,2,3,5,11-15, 17-24 and 26 are rejected under 35 U.S.C. 112, first paragraph, as failing to comply with the written description requirement. The claim(s) contains subject matter which was not described in the specification in such a way as to reasonably convey to one skilled in the relevant art that the inventor(s), at the time the application was filed, had possession of the claimed invention. Applicant claims that device isolation region is spaced apart from the first and second circuit by respective portions of the silicon epitaxial layer. Applicant defines area 5 and 6 in fig. 3 as being these first regions/circuit regions. However regions 5 and 6 are not spaced from device isolation region 7.

3. The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

4. Claims 21 and 23 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention. Applicant claims that the device isolation region is disposed directly adjacent to each of the first and second circuit sections. However the independent claims from which claims 21 and 23 require that the device isolation region

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is spaced apart from the first and second circuit, directly contradicting the limitations of claim 21 and 23. In the interest of compact prosecution, the examiner provisionally interprets the limitation of directly adjacent to mean nearby.

Claim Rejections - 35 USC § 102/103

5. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

6. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

7. Claims 1,5,11-13, 17-26 are rejected under 35 U.S.C. 102(b) as anticipated by or, in the alternative, under 35 U.S.C. 103(a) as obvious over Williams '989.

a. Williams discloses a semiconductor integrated circuit or intermediate semiconductor integrate circuit, comprising: a silicon substrate (111, fig. 25p) having a substantially planar top surface; a silicon epitaxial layer (121,121e, fig. 25p) having a lower resistivity than the resistivity of said silicon substrate (col. 10, lines 50-55) the epitaxial layer having a substantially planar lower epitaxial surface, the epitaxial layer being formed upon the top substrate surface so that the lower epitaxial surface and the top substrate surface are adjacent; a first

(159d, fig. 25p) and second (159b, fig. 25p) circuit section disposed in said silicon epitaxial layer (both sides of ISO layer) forming a first and a second circuit section, each circuit spaced apart from the top substrate surface by a respective portion of the silicon epitaxial layer; and a device isolation region (129a, 125 (center only), fig. 25p) disposed between the first and second circuit sections to electrically separate the first and second circuit sections, the device isolation region extending from a top surface of each of the first and second circuit sections to an inner part of the silicon epitaxial layer formed toward an inner part of the epitaxial layer wherein the device isolation region is spaced apart from the first and second circuit by respective portions of the silicon epitaxial layer. A digital circuit is formed on said first circuit section, and an analog circuit is formed on said second circuit section (circuit can be used in such a fashion). The silicon epitaxial layer is a single layer (fig. 25p). The silicon epitaxial layer is a p-type bulk epitaxial layer (fig. 25p). The silicon substrate comprises a p-type bulk substrate (fig. 25p). The p-type bulk epitaxial layer is formed by a chemical vapor deposition method (see below). The silicon epitaxial layer has a thickness of 5 micrometers (since the ISO regions are graded 129a/125 allow for a thickness of 121/121e of up to 20 microns (col. 13, lines 40-60)) and a resistivity of 10 Ohm—cm (col. 13, lines 40-60). Said silicon substrate and said silicon epitaxial layer are of the same conductivity type (fig. 25p). The device isolation region is disposed nearby to each of the first and second circuit sections (fig. 25p). The device isolation region is disposed entirely between side edges of the

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first and second circuit sections (fig. 25p). The first and the second circuit is a diffusion layer (163c, 159b, fig. 25p) of the same conductive type as the silicon epitaxial layer, and wherein an impurity concentration of the diffusion layer is higher than that of the silicon epitaxial layer. Additionally Williams discloses in the embodiments (especially of fig. 22) wherein the n+ buried layer 123 and 125 maybe optionally deleted (lines 4-10, col. 12).

b. However, assuming *arguendo* that the reference must be so narrowly interpreted so as to mean that Williams fig. 25p does not disclose that that n+ buried layer 123 and 125 may be optionally deleted the claims would not be anticipated. Nonetheless, it would have been obvious to one of ordinary skill in the art the time of the invention to have eliminated at least the n+ buried layer (123, fig. 25p) in Williams in order to reduce fabrication cost/complexity by eliminating the need to form additional diffusion layer(s).

PLEASE NOTE: The recitation of the intended use of the claimed invention must result in a structural difference between the claimed invention and the prior art in order to patentably distinguish the claimed invention from the prior art. If the prior art structure is capable of performing the intended use, then it meets the claim. See, e.g., *In re Pearson*, 18 1 USPQ 641 (CCPA); *In re Minks*, 169 USPQ 120 (Bd Appeals); *In re*

Casey, 152 USPQ 235 (CCPA 1967); *In re Otto*, 136 USPQ 458, 459 (CCPA 1963);
See MPEP §2114. The recitation of the use of individual circuit sections in an
analog/digital fashion, does not distinguish the present invention over Williams 989 who
teaches the structure as claimed.

Claim Rejections - 35 USC § 103

8. Claims 2-3 are rejected under 35 U.S.C. 103(a) as being unpatentable over
Williams '989 in view of Cricchi '349.

c. Williams discloses the device of claims 1 and 13 but does not expressly
disclose that the silicon substrate is between 100 times the resistivity than the
silicon epitaxial layer.

d. Cricchi discloses a semiconductor integrated circuit wherein a silicon
substrate has a resistivity of 1000 Ohm-cm (col. 3).

e. It would have been obvious to one of ordinary skill in the art at the time of
the invention to have modified Williams 10-60 Ohm-cm silicon substrate to a
1000 Ohm-cm substrate in order to reduce interference from other parts of the IC
as well as effective reduction in losses generated by the passive elements (col. 3
of Cricchi).

9. Claim 15 is rejected under 35 U.S.C. 103(a) as being unpatentable over Williams
'989.

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a. Williams discloses the device of claim 13 but does not expressly disclose that the thickness of the substrate is 0.7 mm and has a resistivity of 1000 Ohm-cm.

b. It would have been obvious to one of ordinary skill in the art at the time the invention was made to have made William's substrate thickness 0.7mm and have a resistivity of 1000 Ohm-cm, since it has been held that where the general conditions of a claim are disclosed in prior art, discovering the optimum or working ranges involves only routine skill in the art. In re Aller, 105 USPQ 233 in order to ensure sufficient thickness to reduce interference from other parts of the IC as well as effective reduction in losses generated by the passive elements.

10. Claim 14 is rejected under 35 U.S.C. 103(a) as being unpatentable over Williams '989.

a. Williams discloses the device of claim 13 but does not expressly disclose that the silicon substrate has one hundredth less of an impurity concentration than the silicon epitaxial layer.

b. Nevertheless it would have been obvious to one of ordinary skill in the art at the time the invention was made to have had the silicon substrate one hundredth less of an impurity concentration than the silicon epitaxial layer since it has been held that where the general conditions of a claim are disclosed in prior art, discovering the optimum or working ranges involves only routine skill in the art. In re Aller, 105 USPQ 233. in order to reduce interference from other parts of the IC.

Response to Arguments

Applicant's arguments have been considered but are moot in view of the new ground(s) of rejection.

Conclusion

Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to AMAR MOVVA whose telephone number is (571)272-9009. The examiner can normally be reached on 7:30 AM - 4:30 PM.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Kimberly Nguyen can be reached on 571-272-2402. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

Amar Movva
Examiner
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